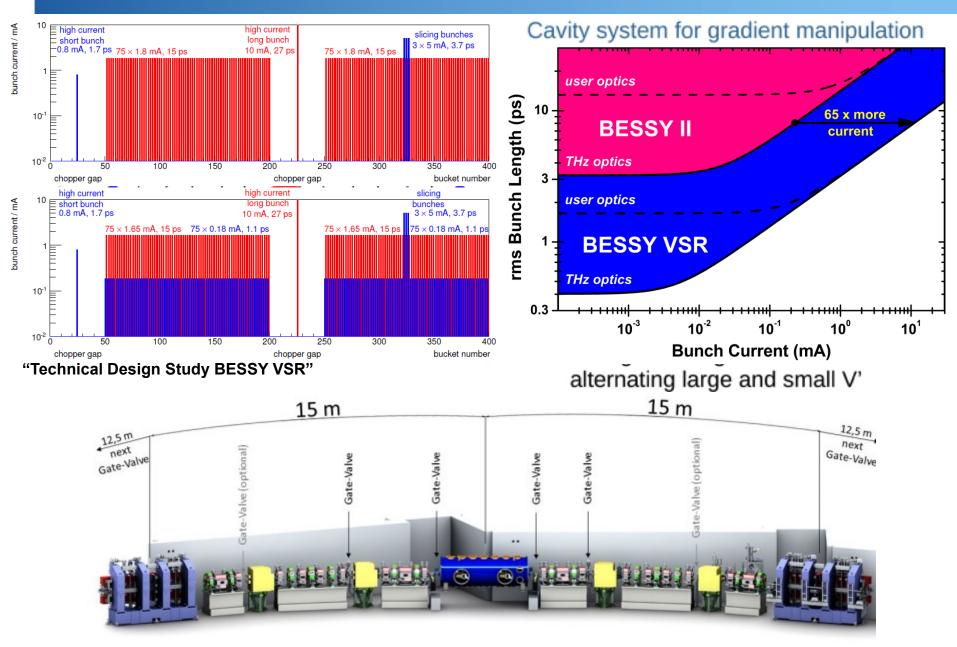


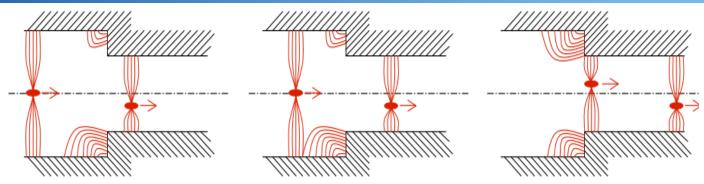
Diagnostics for BESSY VSR, an overview

J.-G. Hwang, G. Schiwietz, M. Koopmans, M. Ries, A. Schälicke, P. Goslawski, T. Atkinson, and beam diagnostics team, BESSY II, Helmholtz-Zentrum Berlin (HZB)

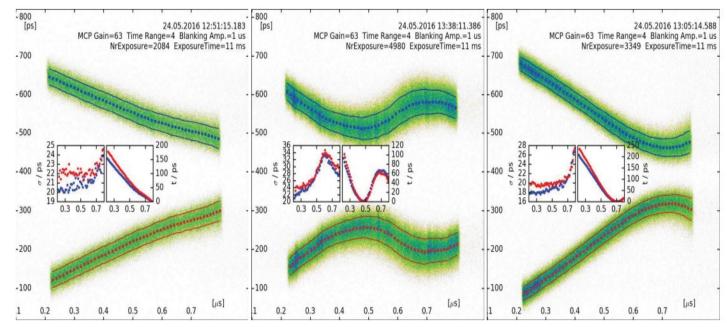
BESSY Variable pulse-length Storage Ring (BESSY VSR)



Transient beam loading



The effect of the beam on the accelerating field is called **BEAM LOADING**. The superposition of the accelerating field established by external generator and the beam induced field needs to be studied carefully in order to obtain the net **Phase** and **Amplitude** of acceleration.



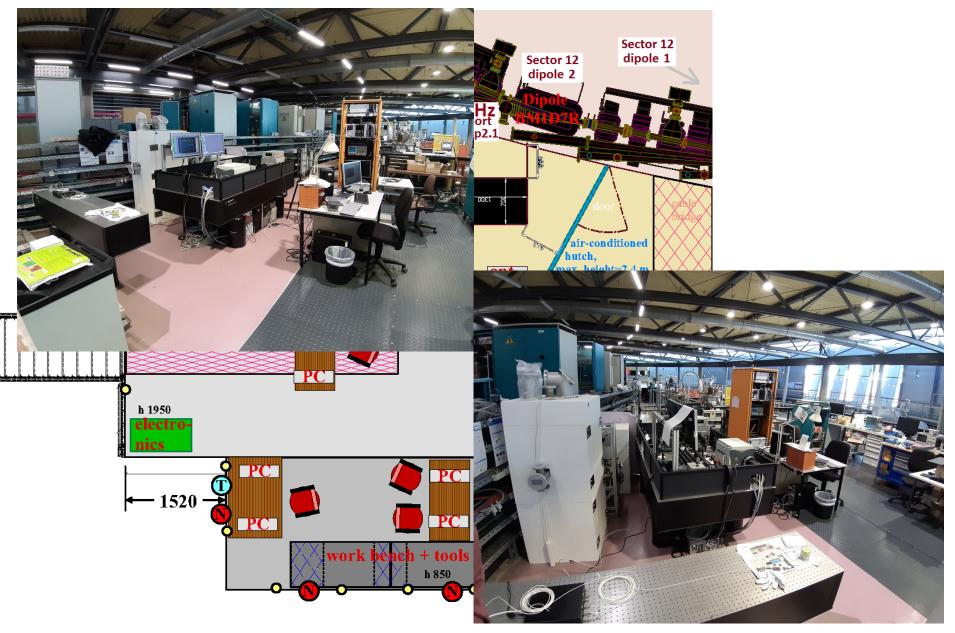
Diagnostics platform refurbish for BESSY VSR

Optical diagnostics



2018 Move to new platform

Diagnostics platform refurbish for BESSY VSR

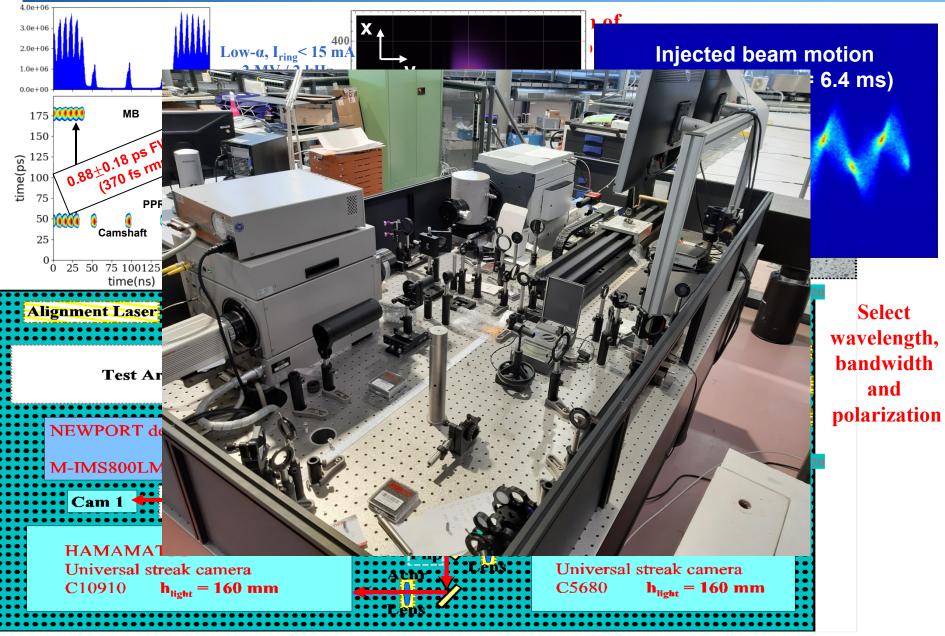


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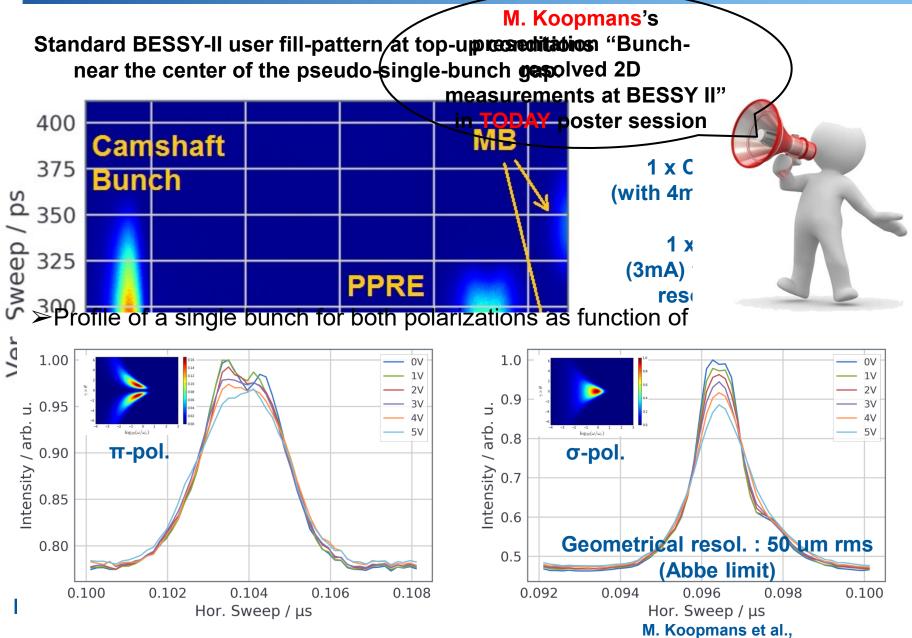
Bunch-resolved temporal distribution monitor

Sector 12 Dip1.1 - BM2T6R Longitudinal Bunch Size **Toroidal Mirror M2** (timing: streak Camera etc.) FWHM = 3.5 14 12 Vertical / mm 10 X-R **Block** 0.0 0.5 1.0 Baf Int. / a.u. 1.00 ntensity Int. / a.r. 0.50 0.25 FWHM = 13.7 Planar **Mirrors** 0.00 M4&M5: 7.5 10.0 12.5 15.0 0.0 2.5 5.0 Horizontal / mm **Select** and Slit Dipolmagnet transverse direction Ellipsoidal **Mirror M1** J.-G. Hwang, ARD topical workshop f

Bunch-resolved temporal distribution monitor



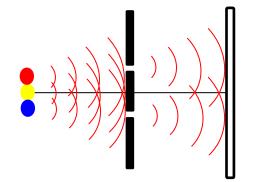
2D (t-x or t-y) measurement



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An interference pattern produced by double with a "point-like" source is given by

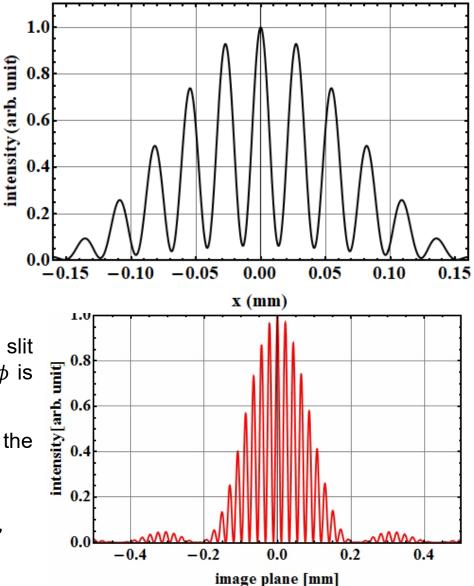
$$I(x) = I_0 sinc^2 \left(\frac{\pi a}{\lambda R}x\right) cos^2 \left(\frac{\pi d}{\lambda R}x + \phi\right),$$

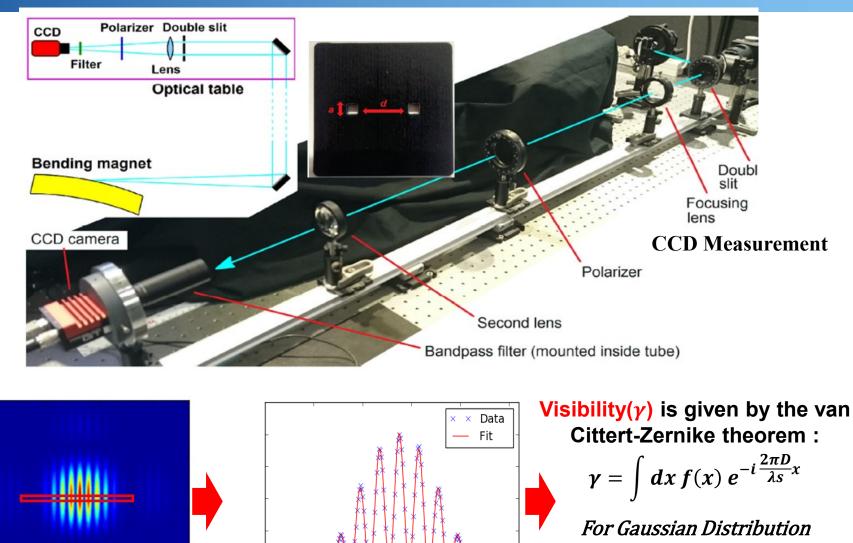
where λ is wavelength, *R* is distance between slit and screen, *d* is slit separation, *a* is slit width, ϕ is phase difference.

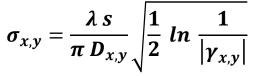
For a **Gaussian distributed light source**, the interference pattern is

$$I(x) = I_0 sinc^2 \left(\frac{\pi a}{\lambda R}x\right) \left(1 + \gamma cos\left(\frac{2\pi d}{\lambda R}x + \phi\right)\right)$$

where γ denotes the visibility.







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5.0

4.5

Position *x*/mm

4.0

).0

0.2

0.4

0.6

Position *x*/mm

0.8

1.0

4.0

3.5

3.0

2.5

3.5

Position y/mm

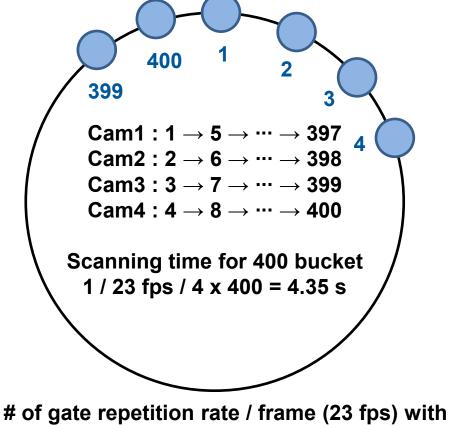


XXRapidFrame Based on 4 x 4 Picos ICCD camera Exposure time: 200 ps to 80 s Delay time: 0s, 10 ps to 80 s Delay and Exposure time step: 10 ps Low jitter : < 10 ps

Multiple gate repetition frequency:

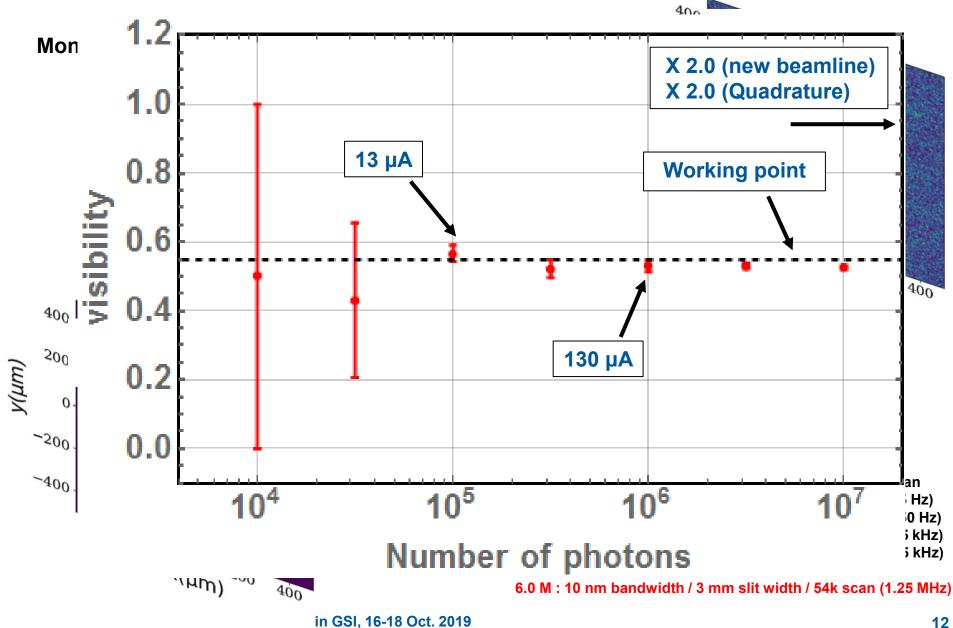
- up to 200 kHz continuous
- up to 3.3 MHz in burst mode
 Pixel size: 8.3 x 8.3 μm
 High dynamic Range: 12 bit

Frame rate:12.5 / 20.0 / 23.0fps



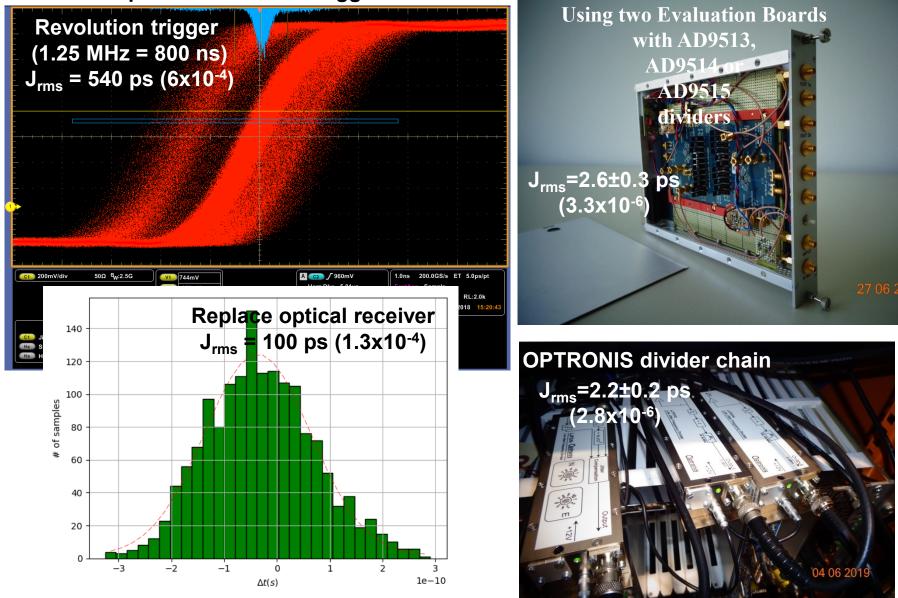
of gate repetition rate / frame (23 fps) with burst mode → 1 / 23 fps * 1.25 MHz = 54 k

of photons / frame (23 fps) with burst mode \rightarrow 5.6 k photons * (area ratio) * 54 k = 6.0 *10⁶ photons / frame



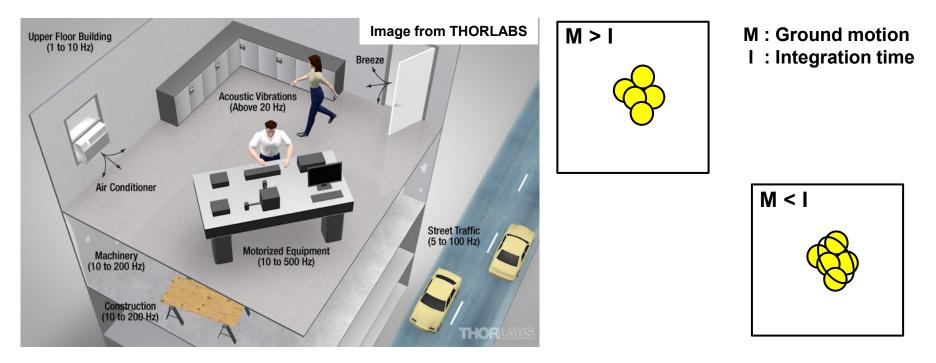
Trigger system upgrade

Needed: improved revolution trigger



Ground motion

Slow motion (ground motion) of an optical table can cause a misleading result of beam diagnostics which is used slow detectors such as CCD that operate in the tens/hundreds of millisecond range.

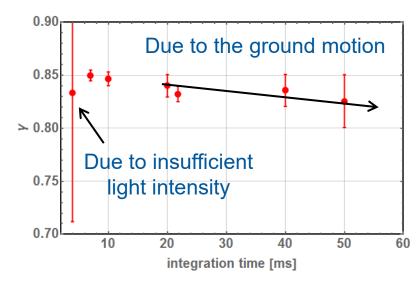


Examples

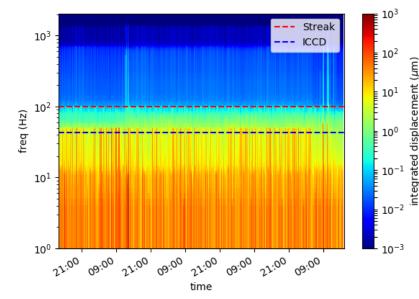
- 1) IBSM (CCD / ICCD) : Visibility reduction \rightarrow Beam size increase
- 2) Pinhole : Beam size increase
- 3) Streak camera : Intensity fluctuation
- 4) Streak camera (+2D measurement) : Beam size increase

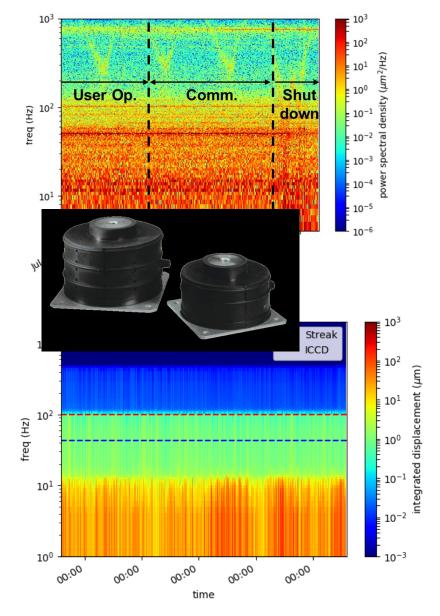
Ground motion

The visibility is measured with various integration time (shutter speed) of the camera.

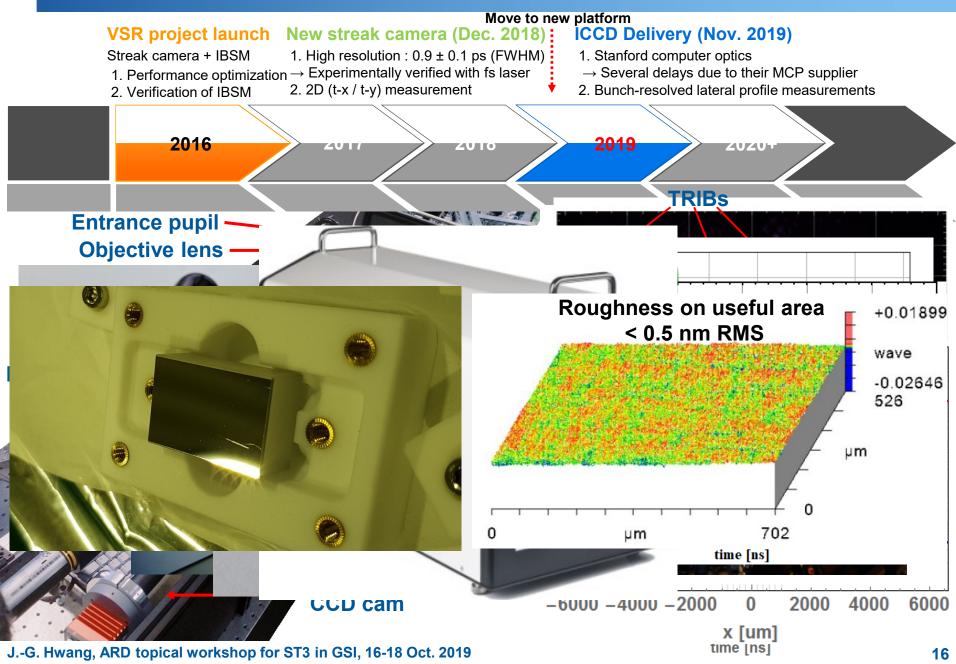


The total(integrated) rms displacement











Thank you for your attention